

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	0	(10/655839).CCLS.	US-PGPU B; USPAT; EPO; JPO	OR	OFF	2004/12/13 07:30
S2	1	10/655839	US-PGPU B; USPAT; EPO; JPO	OR	ON	2004/12/13 12:07
S5	1946	(pressure adj sensor) with (porous porosity bubble cavity void microporous nanoporous)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 17:19
S6	250	S5 and ((pressure adj sensor) with semiconductor)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2004/12/13 13:01
S7	17	S6 and (parallel perpendicular\$2) with (porous porosity bubble cavity void microporous nanoporous)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2004/12/13 12:57
S8	2	S6 and (parallel perpendicular\$2) with ((porous porosity bubble cavity void microporous nanoporous) near3 silicon)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2004/12/13 12:58
S9	1751	S5 and ((pressure adj sensor) with (hollow cavity))	US-PGPU B; USPAT; EPO; JPO	OR	ON	2004/12/13 13:01
S10	701	S9 and layer	US-PGPU B; USPAT; EPO; JPO	OR	ON	2004/12/13 13:02
S11	452	S10 and silicon	US-PGPU B; USPAT; EPO; JPO	OR	ON	2004/12/13 13:03
S12	420	S11 and first	US-PGPU B; USPAT; EPO; JPO	OR	ON	2004/12/13 13:05

S13	404	S12 and second	US-PGPU B; USPAT; EPO; JPO	OR	ON	2004/12/13 13:05
S14	95	S13 and (structure near3 (porous porosity bubble cavity void microporous nanoporous))	US-PGPU B; USPAT; EPO; JPO	OR	ON	2004/12/13 13:08
S15	1	10/655,839	US-PGPU B; USPAT; EPO; JPO	OR	ON	2004/12/13 16:34
S16	2581	(pressure adj sensor) with (hollow cavity pocket)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 17:18
S17	2470	(pressure adj sensor) with (hollow cavity)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:14
S18	666	(pressure adj sensor) with (hollow)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 17:18
S19	1886	(pressure adj sensor) with (cavity)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:19
S20	1897	S16 and (pressure adj sensor) with (porous porosity bubble cavity void microporous nanoporous)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:15
S21	299	S20 and (pressure adj sensor) with (layer film near4 (porous porosity bubble cavity void microporous nanoporous))	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 17:42
S22	299	S21 and (pressure adj sensor layer film porous porosity bubble cavity void microporous nanoporous)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 17:42
S23	269	S22 and first	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:16

S24	257	S23 and second	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 17:42
S25	10	S24 and (pressure adj sensor) with (porous porosity void microporous nanoporous)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:10
S26	2186	(amorphous) near4 (porous porosity void microporous nanoporous)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:25
S27	1318	(amorphous) near2 (porous porosity void microporous nanoporous)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:11
S28	1080	(amorphous) near2 (porous)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:11
S29	694	(amorphous) near (porous)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:13
S30	1	(amorphous near porous) with sensor	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:13
S31	10145	(sensor) near5 (hollow cavity)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:14
S32	6846	S31 and (sensor) near5 (porous porosity bubble cavity void microporous nanoporous)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:16
S33	4722	S32 and (region area)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:17
S34	4300	S33 and first	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:17

S35	4124	S34 and second	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:17
S36	819	S32 and ((region area) near5 first)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:18
S37	552	S36 and ((region area) near5 second)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:18
S38	228	S37 and (pressure adj sensor)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:19
S39	42	S38 and (porous porosity void microporous nanoporous)	US-PGPU B; USPAT; EPO; JPO	OR	ON	2005/06/01 18:25